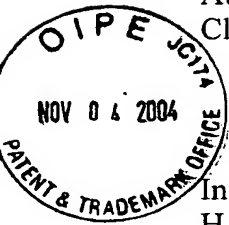


Attorney Docket: 061063-0284101
Client Reference: OSP-11726



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
HASEGAWA et al.

Confirmation Number: 5754

Application No.: 10/021,259

Group Art Unit: 2829

Filed: December 19, 2001

Examiner: Kilday, Lisa A.

Title: METHOD OF PURGING CVD APPARATUS AND METHOD FOR JUDGING
MAINTENANCE OF TIMES OF SEMICONDUCTOR PRODUCTION
APPARATUSES

AMENDMENT UNDER 37 C.F.R. §1.111

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the Office Action dated July 14, 2004, the period for reply being extended to November 14, 2004 by the enclosed Petition for One-Month Extension of Time, please amend the above-identified application as follows: